

SEMICONDUCTOR INTEGRATED CIRCUIT DEVICE

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BACKGROUND OF THE INVENTION

The present invention relates to a semiconductor integrated circuit device and in particular to a semiconductor integrated circuit device
5 having a large chip size and a fine wiring in which a ratio of a wiring delay in a critical path delay time is reduced, thereby improving the operation speed.

Conventionally, the speed of a critical path including a long-distance wiring in a semiconductor
10 integrated circuit device has been improved by (a) improvement of a load drive force of a gate circuit, (b) increase of width of the long-distance wiring, (c) dispersion of output load by gate circuit multiplication, and the like. When the ratio of a
15 wiring delay in the critical path is small as compared to a delay time of the gate circuit, the speed increasing methods (a) to (c) can have a significant effect.

However, the effect of such methods (a) to
20 (c) for increasing the speed becomes smaller as a semiconductor integrated circuit device increases its size and becomes finer. In a gate circuit method for driving all at once multi-fan out long-distance wiring having a large ratio of wiring delay in the critical
25 path as compared to a gate circuit delay time, its

output load is large and its output waveform becomes dull. Furthermore, after passing through the long-distance wiring, the waveform becomes greatly dull due to the wiring RC time constant. The reason of
5 reduction of the effect of the methods (a) to (c) will be detailed below.

Method (a) can have a significant effect while the wiring resistance is sufficiently small as compared to the operation resistance of the load drive
10 transistor of the gate circuit but the wiring resistance cannot be ignored as compared to the operation resistance of the load drive transistor of the gate circuit as the chip size becomes greater and the wiring becomes finer. Thus, method (a) can have an
15 effect for the capacity load but cannot have a significant effect for the resistance load such as the wiring resistance. Method (b) is usually used together with method (a). That is, when method (b) is used to increase the wiring width and reduce the wiring
20 resistance, the load capacity component is increased and accordingly, method (a) is used to increase the speed of the gate circuit for driving the long-distance wiring. However, when the wiring width is increased, although the wiring resistance is reduced, the wiring
25 capacity is increased. Accordingly, the wiring delay time can be approximated by the product of the wiring resistance and the wiring capacity and the improvement of the wiring delay itself is not great. Furthermore,

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method (a) has a limitation from the viewpoint of the area overhead or the power consumption and the effect of increasing the speed is not sufficient. Method (c) or a technique of inserting a relay buffer in the middle of the long-distance wiring for increasing the speed also has a problem that two stages of inverter should be inserted for matching the signal polarity and increasing the speed in all cases is impossible due to the area problem.

10 As has been described above, increase of the wiring delay due to a long-distance wiring and the problem that a path passing through a gate circuit in the vicinity of the long-distance wiring end becomes a critical path go in the opposite direction against fine
15 configuration of a semiconductor integrated circuit. This should be taken into consideration in future.

SUMMARY OF THE INVENTION

It is therefore an object of the present invention to suppress an area overhead, to reduce a
20 ratio of a delay time caused by a wiring resistance in a critical path in a semiconductor integrated circuit, thereby increasing the speed of the critical path, and to increase the operation speed of a semiconductor integrated circuit device.

25 The present invention employs means as follows in order to achieve the aforementioned object.

The present invention provides a

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semiconductor integrated circuit device including a driver circuit 100, a first long-distance wiring 104 connected to the driver circuit 100, and a plurality of gate circuits 103 distributed over and connected to the entire length of the first long-distance wiring 104, wherein an output signal of the driver circuit 100 is received via the first long-distance wiring 104 by the plurality of gate circuits 103, and the driver circuit 100 has an input circuit connected to a node 105 in the vicinity of an input terminal of the gate circuit 103 connected to the end of the first long-distance wiring 104 using a second long-distance wiring 106 and a speed-increasing circuit 107.

According to the present invention, in a gate circuit method for all-at-once driving multiple long-distance wiring fan-outs, a signal change is accelerated not only from one end of the driver circuit 100 but also from the other end by using a second long-distance wiring 106 and a speed-increasing circuit 107 from an early stage, thereby enabling to significantly reduce the wiring delay time and increase the critical path speed as well as to improve the operation speed of the semiconductor integrated circuit device. Moreover, since a waveform in the vicinity of the long-distance wiring end is driven by the speed-increasing circuit arranged physically in the vicinity, the waveform becomes sharp and a high-speed response of the receiver circuit can be obtained.

BRIEF DESCRIPTION OF THE DRAWINGS

Fig. 1 shows a semiconductor integrated circuit device according to a first embodiment of the present invention.

5 Fig. 2 shows a semiconductor integrated circuit device according to a second embodiment of the present invention.

10 Fig. 3 shows a semiconductor integrated circuit device according to a third embodiment of the present invention.

Fig. 4 shows a first application example of the semiconductor integrated circuit device according to the embodiment of the present invention.

15 Fig. 5 shows a semiconductor integrated circuit device according to a fourth embodiment of the present invention.

Fig. 6 shows a semiconductor integrated circuit device according to a fifth embodiment of the present invention.

20 Fig. 7 shows a second application example of the semiconductor integrated circuit device according to the embodiment of the present invention.

Fig. 8 is a timing chart explaining a circuit operation of the second application example of the semiconductor integrated circuit according to the embodiment of the present invention.

25 Fig. 9 shows a third application example of the semiconductor integrated circuit device according

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Fig. 10 shows a semiconductor integrated circuit device according to a sixth embodiment of the present invention.

Description will now be directed to the a semiconductor integrated circuit device as embodiments of the present invention with reference to the attached drawings. In the drawings, like components are denoted
10 by like reference symbols.

Fig. 1 shows a semiconductor integrated circuit device according to a first embodiment of the present invention. In the figure, VIN denotes an input signal, 100 denotes a driver circuit having a CMOS inverter 101, 104 denotes a first long-distance wiring, 103 denotes a plurality of subsequent-stage gate circuits connected at approximately identical interval on the first long-distance wiring 104, 106 denotes a second long-distance wiring, and 107 denotes a speed-increasing circuit having a PMOS transistor 108. This configuration is characterized in that for example, in a drive method for all-at-once driving a plenty of fan-outs and a long-distance wiring such as a memory word line drive method, i.e., in the configuration of the driver circuit 100 for driving the first long-distance wiring 104 and the plurality of gate circuits 103, an input of the driver circuit 100 and an end node 105 of

the first long-distance wiring 104 (the node 105 in the vicinity of the input terminal of the gate circuit 103 arranged physically at the farthest end viewed from an output node 102 of the CMOS inverter 101) is by-passed
5 using the second long-distance wiring 106 and the speed-increasing circuit 107.

Next, explanation will be given on the circuit operation. When the input signal VIN is changed from a high level to a low level, the output
10 node 102 of the CMOS inverter 101 is changed from low to high, and the node 105 is also changed from low to high. Here, the time (wiring delay time) required for the signal change of the node 102 to reach the node 105 is approximately a product of the wiring resistance of
15 the long-distance wiring 104 and the entire capacitance formed on the long-distance wiring 104 (total of the wiring capacity of the long-distance wiring and the input capacity of the plurality of gate circuits 103 which are fan-out of the CMOS inverter 101). On the
20 other hand, when the input signal VIN is changed from high to low, the input node 109 of the speed-increasing circuit 107 via the second long-distance wiring 106 is also changed from high to low. And the PMOS transistor 108 turns on to increase the potential of the node 105
25 to high in the same way as the drive of the aforementioned CMOS inverter 101. In the first long-distance wiring 104 and the second long-distance wiring 106 having an identical length, the wiring delay time

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of the second long-distance wiring 106 is by far shorter than the first long-distance wiring 104 because there is no gate circuit 103 connected as a fan out. Accordingly, when the input signal VIN is changed from high to low, the signal change start time from high to low of the node 109 is by far earlier than the signal change start time of the node 105 changed by the output signal transferred through the long-distance wiring 104 by drive of the CMOS inverter 101 and accordingly, the node 105 can start the signal change by the speed-increasing circuit 107 without waiting for the signal sent through the first long-distance wiring 104. When the input signal VIN is changed from the low level to the high level, the PMOS transistor 108 in the speed-increasing circuit 107 is cut off and the potential of the node 105 is driven only by the CMOS inverter 101 and pulled down from high to low by the first long-distance wiring 104.

Fig. 2 shows a second embodiment of the present invention.

In this embodiment the speed-increasing circuit 107 explained in the first embodiment is realized by an NMOS transistor 110 instead of the PMOS transistor 108. In order to obtain the same circuit operation as the first embodiment, a buffer circuit 111 is provided at the input side of the second long-distance wiring 106 for polarity matching. The other parts of the configuration are identical as the first

embodiment. With this configuration, it is possible to obtain the same effect as the aforementioned first embodiment. It should be noted that in the first embodiment, the first long-distance wiring 104 has an
5 opposite polarity of the second long-distance wiring 106 and there is a danger of generation of a cross talk between the two of the long-distance wiring. In contrast to this, with this configuration the polarities are identical and there is no danger of
10 generating a cross talk between the two of the long-distance wiring.

Fig. 3 shows the third embodiment of the present invention.

In the first embodiment (Fig. 1), the signal
15 change is accelerated by providing the speed-increasing circuit 107 at the node 105 in the vicinity of the input terminal of the gate circuit 103 arranged physically at the farthest end viewed from the output node 102 of the CMOS inverter 101. In this case,
20 however, a path passing through a node in the vicinity of the input terminal of the gate circuit 103 arranged in the middle of the first long-distance wiring 104 becomes a critical path. Accordingly, by additionally inserting a speed-increasing circuit 107 at the
25 position of the node 112 in the vicinity of that gate circuit 103, it is possible to obtain a higher speed than in the first embodiment. This third embodiment of the present invention is shown in Fig. 3.

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The fourth embodiment has a basic configuration identical to the first embodiment (Fig. 1) except for a buffer circuit 200 and a buffer circuit 201 arranged between an input of the driver circuit 100 and an input side end of the second long-distance wiring 106. In the circuit configuration of the first embodiment, the load driven by the driver circuit 100 includes an input capacity of the CMOS inverter 101 and a wiring capacity and resistance of the second long-distance wiring 106. When the load of this second long-distance wiring 106 remarkably increases the delay of the input signal VIN from the drive circuit, eliminating the effect of the speed increase, the present embodiment has a significant effect. That is, by selecting a minimum MOS size of the buffer circuit 200 (and a larger size of the buffer circuit 201) and reducing the load of the second long-distance wiring 106, the buffer circuit 201 can drive the long-distance wiring 106 and the speed-increasing circuit 107 without deteriorating the delay of the input signal VIN. Although a delay overhead equivalent two stages of a buffer circuit is present, by tuning the element device, power source voltage, process, or the buffer circuit and the speed-increasing circuit element size, it is possible to obtain a greater effect than the speed increase by the first embodiment. The operation is identical as the first embodiment and its explanation is omitted here.

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In the aforementioned first to fourth embodiments, the drive method for all-at-once driving a plenty of fan outs and long-distance wiring lines may be a clock distribution method (used in the first application example) having a clock driver for driving a plurality of flip-flops, a memory word line drive method (used in the second application example as will be detailed later), or a path including a driver for driving a plurality of selector circuit control lines.

10 In any of the methods, it is possible to obtain the effects explained in the first to the fourth embodiments and improve the operation speed.

Fig. 6 shows a fifth embodiment of the present invention.

15 This embodiment differs from the aforementioned circuit configuration of the fourth embodiment (Fig. 5) in that the buffer circuit 201 is arranged after the second long-distance wiring 106. That is, by using the buffer circuit 201 to correct the voltage waveform which has passed through the second long-distance wiring 106, before passing the voltage waveform to the speed-increasing circuit 107, the response characteristic of the PMOS transistor 108 is improved. This also increases the voltage response of the node 105 and further reduces the wiring delay of the long-distance wiring 104.

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Fig. 7 shows the second application example of the present invention.

This application example shows the
aforementioned fourth embodiment (Fig. 5) applies to
the memory word line drive method. The circuit
configuration is completely identical to that of the
5 fourth embodiment. The gate circuit 103 is realized by
a memory cell 303, the first long-distance wiring line
104 is realized by a word line WL, and the second long-
distance wiring 106 is realized by a sub-word line.
The memory cell 303 is activated to read out or write
10 in data (word line selected state) when the input
signal VIN is changed from high to low and the word
line WL 104 is changed from low to high. On the
contrary, when the word line WL 104 is changed from
high to low, the memory cell is dis-activated and does
15 not perform data read out or write in (word line non-
selected state).

Next, explanation will be given on the
circuit operation by using the timing chart of Fig. 8.
The figure shows two operation waveforms of the node
20 105. The waveform shown by a dotted line is a waveform
obtained when not providing a by-pass circuit including
buffer circuits 200 and 201, the sub-word line 106, and
the PMOS transistor 108. When the input signal VIN
(word line selecting signal) from a decoding circuit
25 (not depicted) for selecting the word line WL reaches
the word line driver 100 and the input signal VIN is
changed from high to low (word line selected state), an
output node 102 of the word line driver 100 is changed

from low to high. And the node 105 in the vicinity of the input terminal of the memory cell 303 arranged at the farthest bit viewed from the word line driver 100 is also changed from low to high after the wiring delay time of the word line 104. The waveform in the dotted line a dull rise. Accordingly, the response of the memory cell receiving the waveform is slow and the wiring delay time of the word line is great. Next, in the waveform of the node 105 shown by a solid line, when the input signal VIN is changed from high to low, the node 109 via the buffer circuits 200 and 201 and the sub-word line 106 is also changed from high to low, and the PMOS transistor 108 turns on. The word line 104 and the sub-word line 106 have an identical length but the sub-word line 106 has a by far shorter wiring delay time than the word line 104 because no memory cell 303 is connected as fan outs for the number of bits. By tuning the element size of the buffer circuits 200 and 201 and the PMOS transistor 108, the voltage waveform of the node 105 starts rising at an early time as compared to the waveform shown by a dotted line in the figure. Moreover, since drive directly by the PMOS transistor, the waveform rises sharply as compared to the waveform shown by a dotted line, like the rising waveform of the node 102. Accordingly, in the word line WL selected state, the memory cell 303 rapidly reads out, thereby significantly reducing the wiring delay time of the

word line WL. When the input signal VIN turns from low to high (word line non-selected state), the output node 102 of the word line driver 100 turns from high to low. And the memory cell 303 is dis-activated and does not perform data read out. In this case, the PMOS transistor 108 is cut out and the trailing waveform of the node 105 is identical in the dotted line and the solid line in the figure.

Fig. 9 shows a third application example of the present invention.

This application example is a combination of the third embodiment (Fig. 3) and the fourth embodiment (Fig. 5) which is applied to the clock distribution method. In the figure, VCK represents a clock input signal, 100 represents a clock driver circuit, and 203 represents a flip-flop circuit. In this application example, clock input terminals CK of the flip-flop circuit 203 arranged at the farthest end and in the middle viewed from the output of the clock driver circuit 100 are connected by the speed-increasing circuit 107. In this application example, the speed-increasing circuit 107 is inserted at two positions but may be inserted at more positions as has been detailed in the third embodiment and the explanation is omitted here.

Fig. 10 shows a sixth embodiment of the present invention.

In this embodiment, the speed-increasing

circuit 107 explained in the fourth embodiment (Fig. 5) is replaced by a speed-increasing circuit 113 including a CMOS inverter having a PMOS transistor 114 and an NMOS transistor 115.

5 In this embodiment, the operation differs from that of the fourth embodiment in the operation of the speed-increasing circuit 113. When the input signal VIN is changed from low to high, an input node 109 of the speed-increasing circuit 113 via the buffer
10 circuits 200 and 201 and the second long-distance wiring 106 is also changed from low to high and the NMOS transistor of the speed-increasing circuit 113 turns on, thereby decreasing the potential of the node 105 to low (grounding potential) (at this moment, the
15 PMOS transistor 114 is off). When the input signal VIN is changed from high to low, the input node 109 of the speed-increasing circuit 113 is also changed from high to low and the PMOS transistor of the speed-increasing circuit 113 turns on, thereby increasing the potential
20 of the node 105 to high (power supply potential (at this moment, the NMOS transistor 115 is off)).

 Since this embodiment operates as has been described above, this embodiment enables to obtain a high-speed operation at the long-distance wiring
25 voltage change trail in the same way as at its rise in contrast to the aforementioned embodiments which enable to obtain a high-speed operation only at the rise of the long-distance wiring voltage change. Especially in

the second application example (Fig. 7 and Fig. 8), by
configuring the speed-increasing circuit 107 as the
present embodiment, it is possible to obtain a high
speed in the word line non-selected state, too, as in
5 the selected state.

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